

| Ref # | Hits | Search Query | DBs | Default Operator | Plurals | Time Stamp |
|-------|-------|---|-----------------------------|------------------|---------|------------------|
| L1 | 14 | (oxide (silicon near5 oxide)) same (polysilcion (poly near5 crystalline)) same (etch\$3 near5 selectivity) | US-PGPU B; USPAT; USOCR | OR | ON | 2005/02/17 16:04 |
| L2 | 14 | (oxide (silicon near5 oxide)) same (polysilcion (poly near5 crystalline)) same selectivity | US-PGPU B; USPAT; USOCR | OR | ON | 2005/02/17 13:36 |
| L3 | 3 | (oxide (silicon near5 oxide)) near100 (polysilcion (poly near5 crystalline)) near100 selectivity | US-PGPU B; USPAT; USOCR | OR | ON | 2005/02/17 13:37 |
| L4 | 3519 | (oxide (silicon near5 oxide)) near100 (polysilcion silicon (poly near5 crystalline)) near100 selectivity | US-PGPU B; USPAT; USOCR | OR | ON | 2005/02/17 15:55 |
| L5 | 341 | 4 and slurry | US-PGPU B; USPAT; USOCR | OR | ON | 2005/02/17 15:56 |
| L6 | 1469 | (oxide (silicon near5 oxide)) and (polysilcion silicon (poly near5 crystalline)) and selectivity | EPO; JPO; DERWENT ; IBM_TDB | OR | ON | 2005/02/17 15:55 |
| L7 | 57 | 6 and slurry | EPO; JPO; DERWENT ; IBM_TDB | OR | ON | 2005/02/17 15:56 |
| L8 | 44913 | (CMP (chemical near5 mechanical near5 polish\$3)) | US-PGPU B; USPAT; USOCR | OR | ON | 2005/02/17 16:05 |
| L9 | 9102 | 8 and slurry | US-PGPU B; USPAT; USOCR | OR | ON | 2005/02/17 16:06 |
| L10 | 5462 | (438/689-695).CCLS. | US-PGPU B; USPAT; USOCR | OR | OFF | 2005/02/17 16:09 |
| L11 | 1728 | 9 and 10 | US-PGPU B; USPAT; USOCR | OR | ON | 2005/02/17 16:26 |